IDE et al. – U.S. Patent Appln. No. 09/961,409 Attorney Docket No.: 061069-0283750

- Amendment -

IN THE SPECIFICATION

Please amend the Specification as follows:

Please amend paragraph beginning on page 8, line 11, as follows:

-- In Figs. 1 and 2, reference numeral 1 denotes a lower substrate having a control electrode 2, an electronic circuit section 3, a plurality of external lead electrodes 4, and an insulating film I', and 5 denotes an upper substrate provided with external lead electrodes 7 and an electronic circuit section 3' and, as shown in Fig. 2, supporting a flexible thin film 8 including a reflecting surface and an upper substrate electrode 6. In Fig. 3, reference numeral 9 denotes a voltage control circuit provided with a high-voltage source 9a and a reference voltage source 9b to control the voltage of a constant-voltage source 10a applied to the control electrode 2; 10 denotes a high-frequency superposing circuit provided with the constant-voltage source 10a and a high-frequency source 10b to superpose a high-frequency voltage for detecting a static capacitance on the voltage of the constant-voltage source 10a; and 6A denotes a capacitance detecting circuit for detecting a change of the static capacitance between the control electrode 2 and the upper electrode 6. Also, any of the lower substrate, the upper substrate, the voltage control circuit, the high-frequency superposing circuit, and the capacitance detecting circuit is fabricated by means of a well-known semiconductor manufacturing technique. The voltage control circuit and the high-frequency superposing circuit are constructed as the electronic circuit section 3, integrally with the lower substrate 1, by using this technique, and the capacitance detecting circuit can be fabricated integrally with the upper substrate 5 on the electronic circuit section 3' by using the same technique. --

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